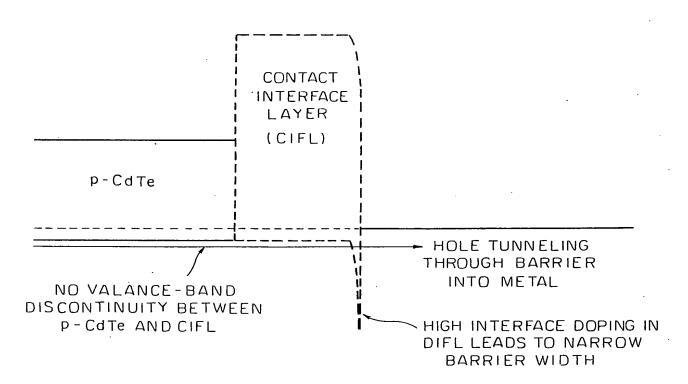
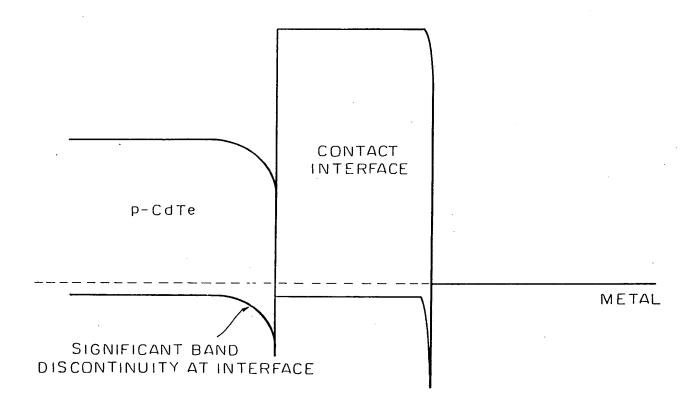


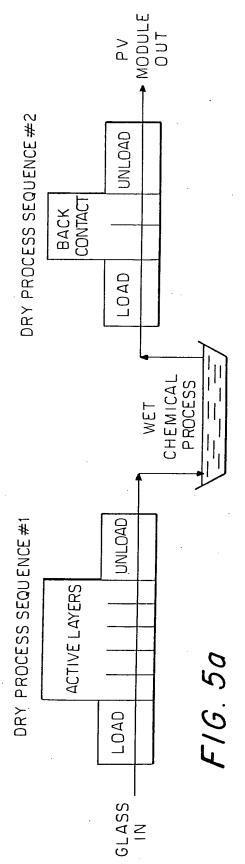
F1G.3

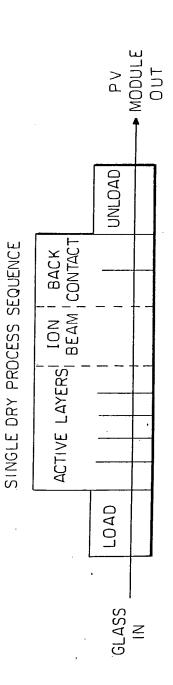


F1G. 4



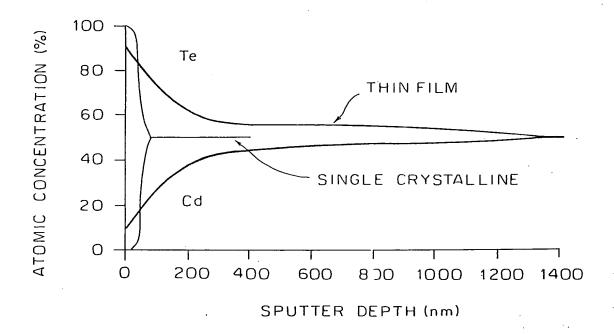
STATE OF THE ART PROCESS SEQUENCE



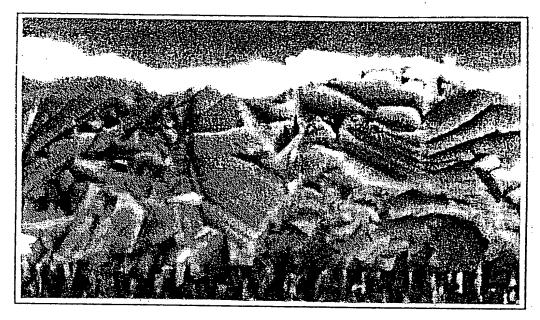


F16.5b

F1G.6

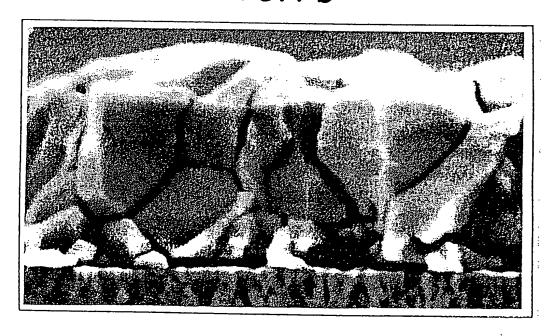


F1G.70

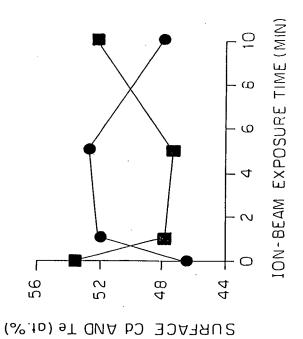


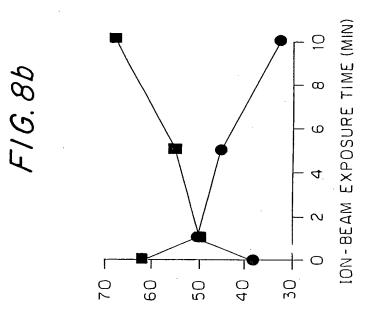
1  $\mu m$ 

F1G. 7b



F16.80





Te BINDING (%)

- Te BOUND TO CADMIUM - Te BOUND TO OXYGEN

% SURFACE Cd

- % SURFACE Te

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F1G. 9

